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(54) **Alignment device which facilitates deposition of organic material through a deposition mask**

(57) An alignment device (10) for permitting a deposition mask (12) to be positioned relative to a substrate to facilitate deposition of organic material on to the substrate which will be part of an organic light emitting device, including a base (14) having a first set of alignment pins (16) and a second set of alignment pins (18); a plate (20) secured to the base (14); a frame (22) having an opening (24) aligned with the plate (20), the frame (22) being formed with a first set of alignment pin receiving holes (17a,17b) corresponding to the position of the first set of pins (16) so that the frame is removably mounted to the base (14); the deposition mask (12) and positioned on the plate (20); a transparent flat plate (28) contacting the second set of pins (18) and the deposition mask (12) and being sized to expose portions of the deposition mask; and securing the exposed portions of the deposition mask to the frame.

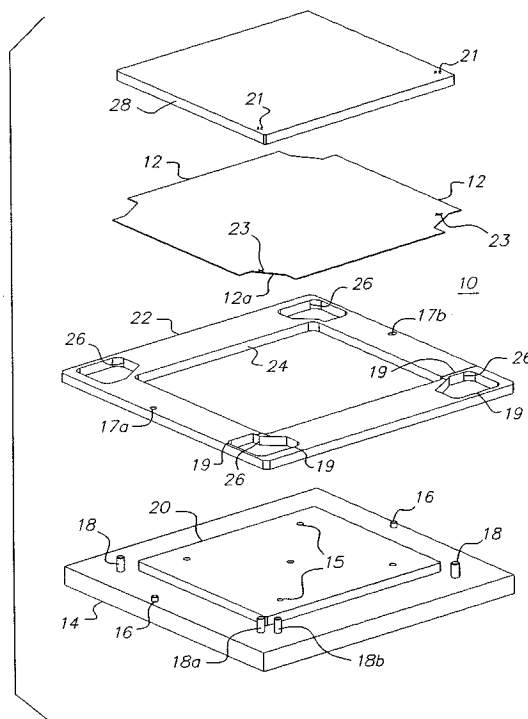


FIG. 1



European Patent
Office

EUROPEAN SEARCH REPORT

Application Number
EP 02 07 7367

DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (IPC)
A	US 4 915 057 A (BOUDREAU ROBERT A [US] ET AL) 10 April 1990 (1990-04-10) * column 2, lines 47-69; figure 1 * * column 4, lines 47-62 * -----	1-8	INV. H01L51/40 H01L51/20
A	US 4 511 599 A (RUSTOMJI SAM H [US]) 16 April 1985 (1985-04-16) * column 4, lines 55-68 - column 5, lines 1-21; figure 3a * -----	1-8	
			TECHNICAL FIELDS SEARCHED (IPC)
			H01L C23C G03F
The present search report has been drawn up for all claims			
Place of search The Hague		Date of completion of the search 27 September 2007	Examiner Faou, Marylène
CATEGORY OF CITED DOCUMENTS X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document			

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**ANNEX TO THE EUROPEAN SEARCH REPORT
ON EUROPEAN PATENT APPLICATION NO.**

EP 02 07 7367

This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report.
The members are as contained in the European Patent Office EDP file on
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27-09-2007

Patent document cited in search report		Publication date	Patent family member(s)	Publication date
US 4915057	A	10-04-1990	NONE	

US 4511599	A	16-04-1985	NONE	

专利名称(译)	有助于通过沉积掩模沉积有机材料的对准装置		
公开(公告)号	EP1276160A3	公开(公告)日	2007-11-14
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申请(专利权)人(译)	伊士曼柯达公司		
当前申请(专利权)人(译)	伊士曼柯达公司		
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CPC分类号	H01L51/56 C23C14/042 H01L51/001		
优先权	09/893250 2001-06-27 US		
其他公开文献	EP1276160A2		
外部链接	Espacenet		

摘要(译)

一种对准装置(10)，用于允许沉积掩模(12)相对于基板定位，以便于将有机材料沉积到基板上，该基板将是有机发光装置的一部分，包括具有基板(14)的基板(14)。第一组定位销(16)和第二组定位销(18)；板(20)固定在基座(14)上；框架(22)，具有与板(20)对齐的开口(24)，框架(22)形成有第一组对准销接收孔(17a，17b)，对应于第一组销的位置(16)使框架可拆卸地安装在底座(14)上；沉积掩模(12)并定位在板(20)上；透明平板(28)，其接触第二组销(18)和沉积掩模(12)，并且其尺寸设计成暴露部分沉积掩模；并将沉积掩模的暴露部分固定到框架上。

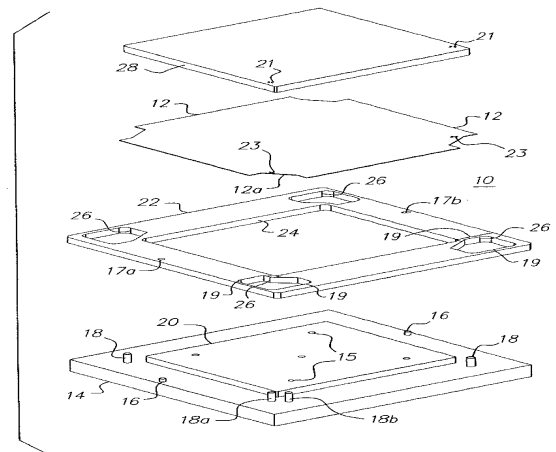


FIG. 1